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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Michael Weber-Grabau et al. PATENT APPLICATION

Serial No.: 09/927,102

Group Art Unit: 2877

Filed: August 10, 2001

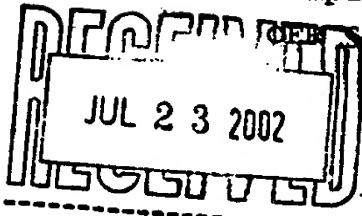
For: OPTICAL CRITICAL DIMENSION METROLOGY SYSTEM  
INTEGRATED INTO SEMICONDUCTOR WAFER PROCESS TOOL

Supplemental Information Disclosure Statement  
with Certification under 37 CFR § 1.97(e)(1)

Hon. Commissioner for Patents  
Washington, D.C. 20231

Sir:

The following information is submitted in  
compliance with Applicants' duty of disclosure under 37  
CFR § 1.97(e). A copy of each reference is enclosed.



U.S. PATENT DOCUMENTS

<u>Patent No.</u>	<u>Patentee</u>	<u>Grant Date</u>
5,233,191	Noguchi, et al	Aug. 3, 1993
5,459,404	Josephs	Oct. 17, 1995
5,994,914	Tsuruta	Nov. 30, 1999

FOREIGN PATENT DOCUMENTS

<u>Publication No.</u>	<u>Publ. Date</u>	<u>Country</u>	<u>Translation</u>
EP 0 991 918	April 12, 2000	EPO	
63 086429	April 16, 1988	Japan	Yes

The undersigned hereby certifies that the items  
of information contained in this Supplemental Information  
Disclosure Statement were cited in a communication  
received from a foreign patent office in a counterpart  
foreign application not more than three months prior to  
the filing of this statement.

2877  
7-24-2

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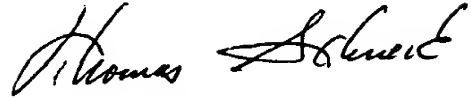
CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231

Signed: Brenda Elmidolan  
Typed Name: Brenda Elmidolan

Date: June 25, 2002

Respectfully submitted,



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FORM PTO-1449	Atty. Docket No. SEN-002	Serial No. 09/927,102
LIST OF PRIOR ART CITED BY APPLICANT	Applicant: Michael Weber-Grabau et al.	
	Filing Date: August 10, 2001	Group: 2877

## U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Grant Date	Name	Class	Sub Class	Filing Date
AA	5,233,191	8/3/93	Noguchi et al.	250	306	4/2/91
AB	5,459,404	10/17/95	Josephs	324	751	3/28/94
AC	5,994,914	11/30/99	Tsuruta	324	765	7/25/97
AD						
AE						
AF						
AG						
AH						
AI						
AJ						

## FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Publ. Date	Country	Class	Sub Class	Translation Yes No
AK	0 991 918	4/12/00	EPO			
AL	63 086429	4/16/88	Japan			X
AM						
AN						

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AO	
AP	
AQ	

EXAMINER:

DATE CONSIDERED:

\*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.